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Nanoengineering: Fabrication, Properties, Optics, and Devices X

Eva M. Campo
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Contents

vii *Conference Committee*

SESSION 1 NANOFLUIDIC, LIQUID CRYSTAL, AND ORGANIC DEVICES

8816 02 **High volume nanoscale roll-based imprinting using jet and flash imprint lithography (Invited Paper)** [8816-1]
S. H. Ahn, M. Miller, S. Yang, M. Ganapathisubramanian, M. Menezes, V. Singh, J. Choi, F. Xu, D. LaBrake, D. J. Resnick, S. V. Sreenivasan, Molecular Imprints, Inc. (United States)

8816 06 **Impact of the Marangoni effect on the polymer thin film thickness profile after drying polymer solution coated on a flat substrate** [8816-6]
H. Kagami, Nagoya College (Japan)

8816 07 **Electrically tunable diffraction grating** [8816-7]
S. I. Kim, J. H. Choi, H. Y. Ahn, C. W. Baik, J. An, C.-S. Choi, K. Pyun, H.-S. Lee, Samsung Advanced Institute of Technology (Korea, Republic of)

8816 08 **Optical microscope combined with the nanopipette-based quartz tuning fork-atomic force microscope for nanolithography** [8816-61]
S. An, Seoul National Univ. (Korea, Republic of); C. Stambaugh, National Institute of Standards and Technology (United States); S. Kwon, K. Lee, B. Kim, Q. Kim, W. Jhe, Seoul National Univ. (Korea, Republic of)

SESSION 2 NANOFABRICATION, NANOSTRUCTURES, AND NANOPARTICLES

8816 0D **The cause of irregular shape of the photonic crystal fabricated with recycled solvent** [8816-13]
J.-H. Choi, Korea Atomic Energy Research Institute (Korea, Republic of); K.-S. Kang, Kyungil Univ. (Korea, Republic of)

8816 0H **Fabrication and characterization of nanostructure thin film ZnO Schottky contacts based UV photodetectors** [8816-62]
G. M. Ali, Al-Mustansiriyah Univ. (Iraq); P. Chakrabarti, Institute of Technology, Banaras Hindu Univ. (India)

SESSION 3 OPTICAL NANODEVICES

8816 0J **Generation and collision of optical similaritons in dispersion-engineered silicon photonic nanowires** [8816-19]
S. Lavdas, Univ. College London (United Kingdom); J. B. Driscoll, R. R. Grote, R. M. Osgood Jr., Columbia Univ. (United States); N. C. Panoiu, Univ. College London (United Kingdom)

8816 0K **Fast and high accuracy FDTD using numerical Green's functions based on a nonstandard finite difference model for photonics design** [8816-20]
J. B. Cole, N. Okada, Univ. of Tsukuba (Japan)

8816 0L **Optical mode modulation of AlGaInP multi quantum well laser diodes** [8816-21]
C.-T. Hung, S.-C. Huang, T.-C. Lu, National Chiao Tung Univ. (Taiwan)

8816 0N **Theoretical and experimental investigation of evanescent-wave absorption sensors for extreme temperature applications** [8816-23]
M. Buric, National Energy Technology Lab. (United States); P. Ohodnicki, National Energy Technology Lab. (United States) and Carnegie Mellon Univ. (United States); B. Chorpening, National Energy Technology Lab. (United States)

SESSION 4 ENERGY AND ENVIRONMENT NANOTECHNOLOGIES

8816 0P **Effects of quantum efficiency on PbSe/PbSrSe multiple quantum well structures** [8816-26]
M. Khodr, American Univ. of Ras Al Khaimah (United Arab Emirates)

8816 0Q **Fabrication and characterization of nanostructured III-V thermoelectric materials** [8816-59]
C. Novotny, National Institute of Standards and Technology (United States) and Univ. of Maryland, College Park (United States); F. Sharifi, National Institute of Standards and Technology (United States)

SESSION 5 NANOENGINEERED OPTICAL FILMS

8816 0U **Nano fabrication of high efficiency stacked crystal zone plate for x-ray optics** [8816-30]
A. V. Kuyumchyan, American NanoScience and Advanced Medical Equipment (United States); L. A. Haroutunyan, Yerevan State Univ. (Armenia); K. G. Trouni, Institute of Applied Problems of Physics (Armenia); A. K. Truni, Yerevan State Medical Univ. (Armenia); R. Z. Gaprelyan, Yerevan State Univ. (Armenia); D. A. Kuyumchyan, California State Univ. (United States); A. Abramyan, Univ. of California, Irvine (United States)

SESSION 6 NANOMECHANICS

8816 0V **Multi-stimuli-responsive elastomeric opal films: processing, optics, and applications (Invited Paper)** [8816-31]
C. G. Schäfer, M. Gallei, G. P. Hellmann, M. Biesalski, M. Rehahn, Technische Univ. Darmstadt (Germany)

8816 0X **Nano plasmon device fabrications using dielectrophoretic (DEP) force** [8816-33]
J. Kim, Korea Univ. (Korea, Republic of) and Korea Institute of Science and Technology (Korea, Republic of); C.-M. Kang, S. Kim, Korea Univ. (Korea, Republic of); J. F. Suh, H. J. Shin, Korea Institute of Science and Technology (Korea, Republic of); J. H. Park, Korea Univ. (Korea, Republic of)

SESSION 7 SUB-WAVELENGTH DEVICES

8816 0Z **Theoretical characteristics of 1.55 μm InN based quantum dot laser** [8816-34]
M. M. Hossain, The Univ. of New Mexico (United States); M. A. Al-Humayun, Univ. Malaysia Perlis (Malaysia); A. G. Bhuiyan, Khulna Univ. of Engineering & Technology (Bangladesh)

8816 12 **Nonlinear phenomena from a PIC-attached gold tip using a plasmonic-whispering gallery mode hybrid system** [8816-37]
F. Ren, H. Takashima, Y. Tanaka, H. Fujiwara, K. Sasaki, Hokkaido Univ. (Japan)

8816 13 **Generation and performance of localised surface plasmons utilising nano-scale structured multi-layered thin films deposited upon D-shaped optical fiber** [8816-38]
T. Allsop, Aston Univ. (United Kingdom); R. Neal, Plymouth Univ. (United Kingdom); C. Mou, Aston Univ. (United Kingdom); M. Dvorak, Brno Univ. of Technology (Czech Republic); A. Rozhin, Aston Univ. (United Kingdom); K. Kalli, Cyprus Univ. of Technology (Cyprus); D. J. Webb, Aston Univ. (United Kingdom)

8816 14 **Tilted exposure microsphere nanolithography for high-throughput and mask-less fabrication of plasmonic molecules** [8816-39]
A. Bonakdar, S. J. Jang, H. Mohseni, Northwestern Univ. (United States)

POSTER SESSION

8816 17 **Signature geometry and quantum engineering** [8816-43]
S. Samociuk, Penlon Farm (United Kingdom)

8816 19 **Predefined planar structures in semiconductor surfaces patterned by NSOM lithography** [8816-45]
I. Lettrichova, D. Pudis, Univ. of Žilina (Slovakia); A. Laurencikova, S. Hasenohrl, J. Novak, Institute of Electrical Engineering (Slovakia); J. Skriniarova, J. Kovac, Slovenska Technicka Univ. (Slovakia)

8816 1A **Emission properties of surface patterned LEDs** [8816-46]
D. Pudis, Univ. of Žilina (Slovakia); P. Hronec, J. Kovac, Slovenska Technicka Univ. (Slovakia); I. Lettrichova, Univ. of Žilina (Slovakia); J. Skriniarova, Slovenska Technicka Univ. (Slovakia); D. Jandura, S. Slabeyciusova, L. Suslik, Univ. of Žilina (Slovakia); J. Novak, Institute of Electrical Engineering (Slovakia); A. Kuzma, Slovenska Technicka Univ. (Slovakia)

8816 1B **Nanostencil lithography for fabrication of III-V nanostructures** [8816-48]
K. Vora, F. Karouta, Australian National Fabrication Facility (Australia); C. Jagadish, Australian National Fabrication Facility (Australia) and The Australian National Univ. (Australia)

8816 1D **Polydimethylsiloxane fibers for optical fiber sensor of displacement** [8816-51]
I. Martincek, D. Pudis, P. Gaso, Univ. of Žilina (Slovakia)

8816 1E **Optical properties of subwavelength patterned metal gratings for photonic device application and an alternative proposal** [8816-52]
H.-K. Lyu, S. Woo, Daegu Gyeongbuk Institute of Science & Technology (Korea, Republic of); S.-H. Jo, J.-K. Shin, Kyungpook National Univ. (Korea, Republic of)

8816 1F **Titanium dioxide fine structures by RF magnetron sputter method deposited on an electron-beam resist mask** [8816-53]
H. Hashiba, Y. Miyazaki, Nihon Univ. (Japan); S. Matsushita, Tokyo Institute of Technology (Japan)

8816 1G **Optical properties of aqueous dispersions of diamond nanoparticles** [8816-54]
A.-S. Popescu, The City College of New York (United States); B. Penkov, Phoebus Optoelectronics, LLC (United States); Y. U. Jung, The City College of New York (United States); R. Akhmechet, Phoebus Optoelectronics, LLC (United States); A. B. Golovin, D. T. Crouse, The City College of New York (United States) and Ctr. for Metamaterials (United States)

8816 1H **A tunable inverse-hemisphere-shaped Bragg grating sensor** [8816-55]
Y. Ryu, K. Kim, Yonsei Univ. (Korea, Republic of)

8816 1I **Piezoelectricity of ZnO nano-rods array prepared by hydrothermal method** [8816-56]
S. H. Kim, T. U. Kim, H. C. Ki, D. G. Kim, J. H. Choi, Korea Photonics Technology Institute (Korea, Republic of); J. H. Kim, Chonnam National Univ. (Korea, Republic of)

8816 1K **Contamination control in ion beam sputter-deposited films** [8816-58]
D. I. C. Pearson, S. Pochon, M. Cooke, Oxford Instruments Plasma Technology (United Kingdom)

8816 1L **Effect of laser fluence and shot numbers on the diameter of hole in gold film** [8816-15]
Y. Wang, Y. Gao, Heilongjiang Univ. (China); J. Zu, Shanghai Institute of Optics and Fine Mechanics (China)

Author Index

Conference Committee

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1 Nanofluidic, Liquid Crystal, and Organic Devices
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2 Nanofabrication, Nanostructures, and Nanoparticles
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3 Optical Nanodevices
Louay A. Eldada, Quanergy, Inc. (United States)

4 Energy and Environment Nanotechnologies
Louay A. Eldada, Quanergy, Inc. (United States)

5 Nanoengineered Optical Films
Elizabeth A. Dobisz, HGST (United States)

6 Nanomechanics
Elizabeth A. Dobisz, HGST (United States)

7 Sub-Wavelength Devices
Elizabeth A. Dobisz, HGST (United States)